



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Smith, *et al.*

Docket No.: 2001 P 11900 US01

Serial No.: 10/786,996

Art Unit: 1746

Filed: February 25, 2004

Examiner: TBD

For: Method of Removing PECVD Residues of Fluorinated Plasma Using In-SITU H₂ Plasma

Mail Stop Missing Parts
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL PRELIMINARY AMENDMENT

Dear Sir:

Prior to examination on the merits, Applicants respectfully submit this Preliminary Amendment as set forth below: